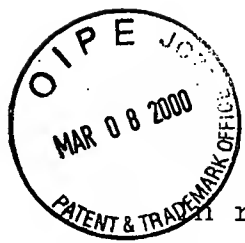


GAV 2879

35.C10499 CONT. I/DIV. I

PATENT APPLICATION



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

re Application of:)
: Examiner: M. Gerike
HIDEAKI MITSUTAKE, ET AL.)
: Group Art Unit: 2879
Application No.: 09/045,681)
:
Filed: March 23, 1998)
:
For: ELECTRON BEAM APPARATUS) March 8, 2000
AND IMAGE FORMING)
APPARATUS)

The Assistant Commissioner for Patents
Washington, D.C. 20231

SUBMISSION OF INFORMATION

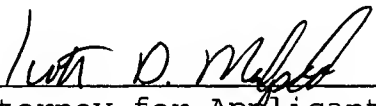
Sir:

Enclosed for the Examiner's information is a Chinese Office Action that was received in connection with the corresponding Chinese application. As indicated, the communication was mailed on January 14, 2000.

All of the documents identified on the Chinese Office Action are of record in the subject application. For this reason, submitting the Office Action in an Information Disclosure Statement pursuant to 37 C.F.R. §1.97 is deemed to be unnecessary.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our below-listed address.

Respectfully submitted,



Attorney for Applicants

Registration No. 32,533

FITZPATRICK, CELLA, HARPER & SCINTO
30 Rockefeller Plaza
New York, New York 10112-3801
Facsimile: (212) 218-2200

SDM\rnm